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Correction: An elastomer for epidermal electronics with adjustable adhesion force and stretchability obtained via a reverse-micelle-induced process

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Correction for 'An elastomer for epidermal electronics with adjustable adhesion force and stretchability obtained via a reverse-micelle-induced process' by Junhyung Kim *et al.*, *J. Mater. Chem. C*, 2018, 6, 2210–2215.

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The Royal Society of Chemistry apologises for these errors and any consequent inconvenience to authors and readers.

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